

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) 3579.2US (98-0062.02/US)		Application Number N t Y t Assigned 10/729/12	
				Applicant Dapeng Wang		Filing Date December 5, 2003	
				Group Art Unit Unknown			

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
BB	5,232,875	08/1993	Tuttle et al.			
BB	5,514,245	05/1996	Doan et al.			
BB	5,624,299	04/1997	Shendon			
BB	5,664,989	09/1997	Nakata et al.			
BB	5,692,947	12/1997	Talieh et al.			
BB	5,692,950	12/1997	Rutherford et al.			

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
BB	57023965 A	02/1982	JP		*		
BB	58045861 A	03/1983	JP		*		

OTHER DOCUMENTS		(Including Author, Title, Date, Pertinent Pages, Etc.)
BB		Wang et al., <u>Von Mises Stress in Chemical-Mechanical Polishing Processes</u> , J. Electrochem. Soc., Vol. 144, No. 3, March 1997 pp. 1121-27.

EXAMINER	DATE CONSIDERED 11/26/04
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EXAMINER: Initial if citation consid red, wheth r or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not consid red. Includ copy f this form with next communication t the applicant.